

DOCKET NO.: 221158US2PCT

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

IN RE APPLICATION OF: Yasutaka ITO, et al.

SERIAL NO.: NEW U.S. PCT APPLICATION

FILED: HERewith

INTERNATIONAL APPLICATION NO.: PCT/JP01/06395

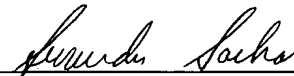
INTERNATIONAL FILING DATE: July 25, 2001

FOR: CERAMIC SUBSTRATE, CERAMIC HEATER, ELECTROSTATIC CHUCK AND  
SUBSTRATE FOR WAFER PROBER FOR SEMICONDUCTOR MANUFACTURE AND  
INSPECTION**REQUEST FOR PRIORITY UNDER 35 U.S.C. 119**  
**AND THE INTERNATIONAL CONVENTION**Assistant Commissioner for Patents  
Washington, D.C. 20231*J. Kwon*  
#6  
9/16/2002

Sir:

In the matter of the above-identified application for patent, notice is hereby given that  
the applicant claims as priority:**COUNTRY**  
Japan**APPLICATION NO**  
2000-223767**DAY/MONTH/YEAR**  
25 July 2000Certified copies of the corresponding Convention application(s) were submitted to the  
International Bureau in PCT Application No. PCT/JP01/06395. Receipt of the certified  
copy(s) by the International Bureau in a timely manner under PCT Rule 17.1(a) has been  
acknowledged as evidenced by the attached PCT/IB/304.Respectfully submitted,  
OBLON, SPIVAK, McCLELLAND,  
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